

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

KANAYA et al.

Serial No.: TBA

Filed: June 25, 2003

For: Semiconductor Device Having Ferroelectric Capacitor and Hydrogen Barrier
Film and Manufacturing Method Thereof

Atty. Docket No.: 002372.00043

Group Art Unit: TBA

Examiner: TBA

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Preliminary to the examination of the above-identified application, kindly amend the application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims begin on page 8 of this paper.

Amendments to the Title begin on page 9 of this paper.

Remarks begin on page 10 of this paper.